

Low thermal conductivity and high carrier mobility in type-II Dirac semimetal PtTe₂ thin films

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Supporting Information

We re-measured the average thickness of the MBE-grown PtTe₂ thin film using a SuperView W1 optical 3D profilometer (CHOTEST Technology Inc., Shenzhen, China; vertical resolution: 0.1 nm) based on white-light interferometry. The average thickness measured over a large area of the PtTe₂ thin film is approximately 5.3 nm, as presented in **Figure S1a**. The measurement results are consistent with our previous measurements of PtTe₂ thickness obtained using cross-sectional scanning transmission electron microscopy (STEM) [1]. Meanwhile, after comparing the obtained XRD characterization data in PtTe₂ with the standard PDF card (No. 18-0977), we found that the characteristic diffraction peaks of the hexagonal PtTe₂ are largely consistent as shown in **Figure S1b**. This result is consistent with previously reported findings [1, 2].

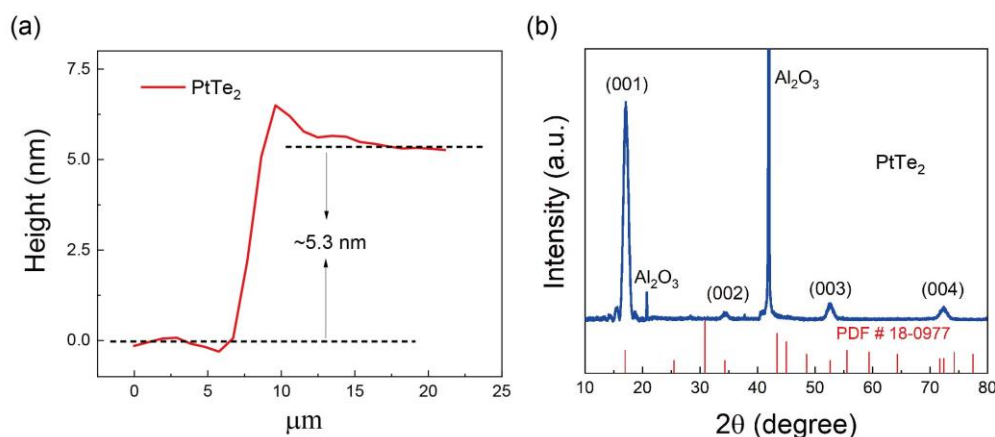


Figure S1. (a) The step height indicates a thickness of 5.3 nm in PtTe₂ film. (b) XRD pattern of the PtTe₂ thin films epitaxially grown on an Al₂O₃ substrate.

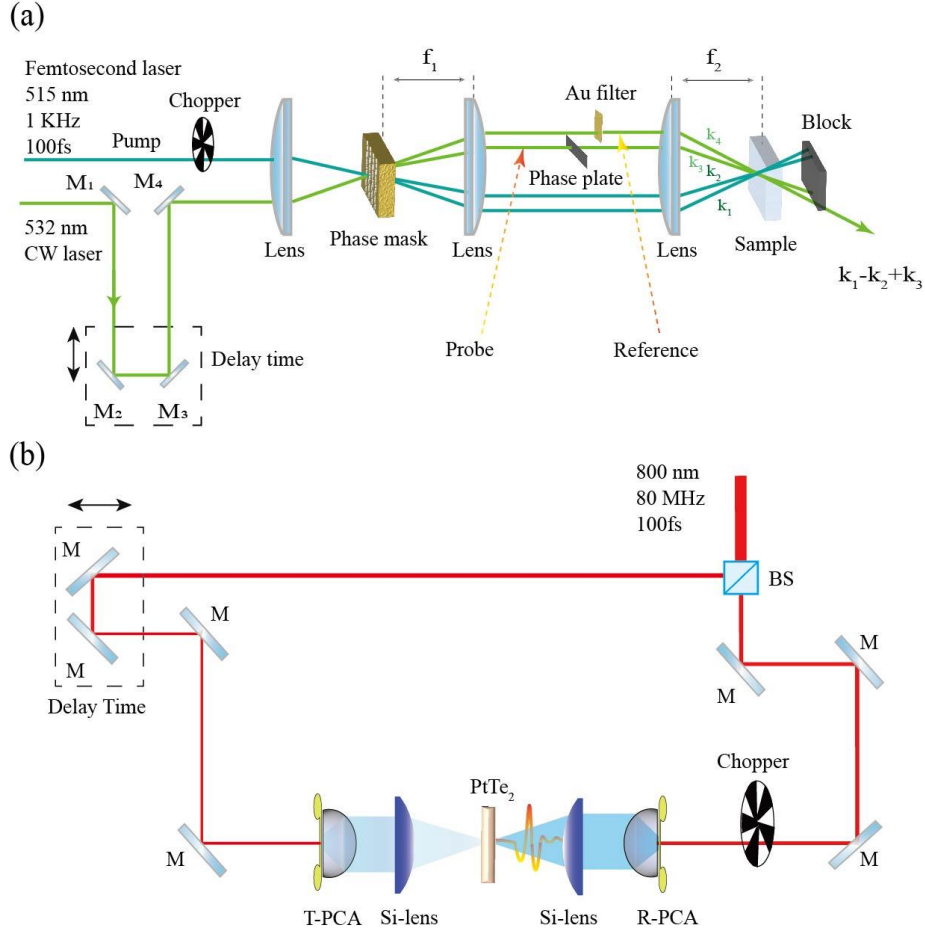


Figure S2. (a) Schematic illustration of a typical transient thermal grating experiment. (b) Schematic diagram of the THz-TDS experimental system based on a low-temperature grown gallium arsenide photoconductive antenna detection.

Conductivity measurements of the epitaxial Dirac semimetal PtTe_2 as shown in Figure S3 were performed in a Physical Property Measurement System (Quantum Design, PPMS DynaCool).

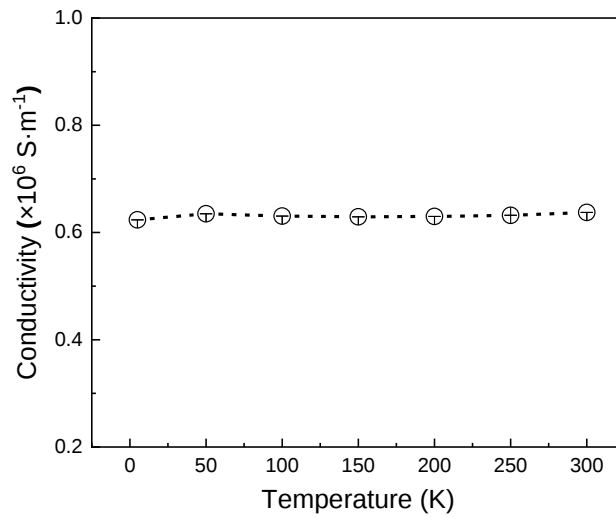


Figure S3. Temperature-dependent conductivity of the PtTe_2 thin films.

The Seebeck coefficient were measured simultaneously using a ZEM-3 system (ULVAC-RIKO, Japan) with a four-probe method as shown in Figure S4.

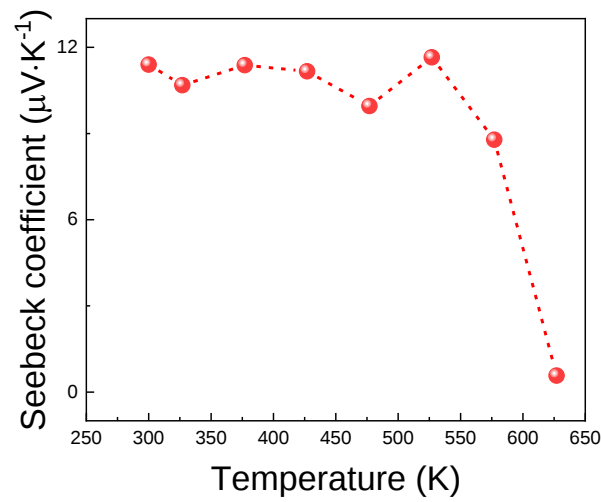


Figure S4. The Seebeck coefficient of PtTe₂ thin films as a function of temperature.

References

- [1] Chen M. Y., Jiang T. R., Wang J. L., et al. Giant Photogalvanic Effect-Induced Terahertz Wave Emission in Wafer-Scale Type-II Dirac Semimetal PtTe. *Acs Applied Materials & Interfaces* **2025**,17, 4137.
- [2] Ma H., Chen P., Li B., et al. Thickness-Tunable Synthesis of Ultrathin Type-II Dirac Semimetal PtTe₂ Single Crystals and Their Thickness-Dependent Electronic Properties. *Nano Lett.* **2018**,18, 3523.